

### Amendment to Claims

1 (canceled).

2 (currently amended). An apparatus for moving an article through plasma, the apparatus comprising:

a first arm rotatable around a first axis;

a second arm rotatably attached to the first arm to rotate an article around a second axis; and

a rotational mechanism for inducing a rotational motion of the article in addition to, and simultaneously with, the rotation of the first and second arms, the rotational mechanism comprising ~~a non-contact~~ an article holder for holding the article, the article holder comprising a body for emitting one or more gas flows towards the article to develop vacuum to hold the wafer adjacent to the body, the one or more gas flows preventing the article from contacting the body, the article holder comprising one or more rotatable pins each of which is for being positioned on a side of the article, each pin being drivable to rotate around a corresponding axis passing through the pin and to thereby rotate the article when the article is pressed against the pin by a centrifugal force developed by the rotation of the second arm.

3 (previously presented). The apparatus of Claim 2 further comprising a body fixedly attached to the first arm;

wherein the rotational mechanism comprises a link coupled to the body and at least one of the pins.

4 (previously presented). The apparatus of Claim 3 wherein the link is driven by the at least one of the pins due to the rotation around the second axis, and the link causes the at least one of the pins to rotate the article due to (i) coupling between the link and the body and (ii) coupling between the link and the at least one of the pins.

5-8 (canceled).

9 (original). The apparatus of Claim 2 further comprising a plasma source for generating the plasma, wherein the article has a surface all of which is to be processed with the plasma, but at any time when the plasma contacts the article, a distance between the first

axis and a plasma region contacting the article is greater than a distance between the first axis and said surface.

10 (original). The apparatus of Claim 2 further comprising a plasma source for generating the plasma, wherein the article has a surface all of which is to be processed with the plasma, but at any given time at most a portion of said surface is in contact with the plasma.

11 (original). The apparatus of Claim 10 wherein at any given time T1 when the surface is in contact with the plasma, the surface has points moving at different speeds, and the point which has the lowest speed at the time T1 is not contacted by the plasma, but said point is contacted by the plasma at other time when said point is not the point having the lowest speed.

12 (original). The apparatus of Claim 2 further comprising a plasma source for generating a plasma jet which is too narrow to cover the article, the apparatus being for moving the article in and out of the plasma jet.

13 (original). The apparatus of Claim 2 wherein the article processing is performed at atmospheric pressure.

14 (original). The apparatus of Claim 2 wherein the article processing is an etch.